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Docket: 0819-442

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

JC916 U.S. PTO
09/692211
10/20/00



In re New Patent Application of)
Akihiko ISHIBASHI et al.)
Japanese Priority Application No. 11-299640) Attn: Applications
Japanese Priority Date: October 21, 1999) Branch
For: METHOD OF FABRICATING)
NITRIDE SEMICONDUCTOR)
DEVICE) Date: October 20, 2000

INFORMATION DISCLOSURE STATEMENT

Honorable Assistant Commissioner for Patents
Washington, D.C. 20231

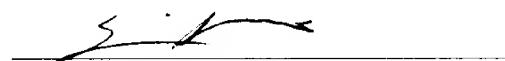
Sir:

In accordance with the provisions of 37 C.F.R. 1.56 and 37 C.F.R. 1.97-1.99, it is requested that the references listed on the attached Form PTO-1449 be made of record in the above-identified application.

Copies of the references are submitted herewith in accordance with 37

C.F.R. 1.98(a).

Respectfully submitted,


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